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(54) **Title:** EXTRUSION-BASED ADDITIVE MANUFACTURING SYSTEM FOR 3D STRUCTURAL ELECTRONIC, ELECTROMAGNETIC AND ELECTROMECHANICAL COMPONENTS/DEVICES

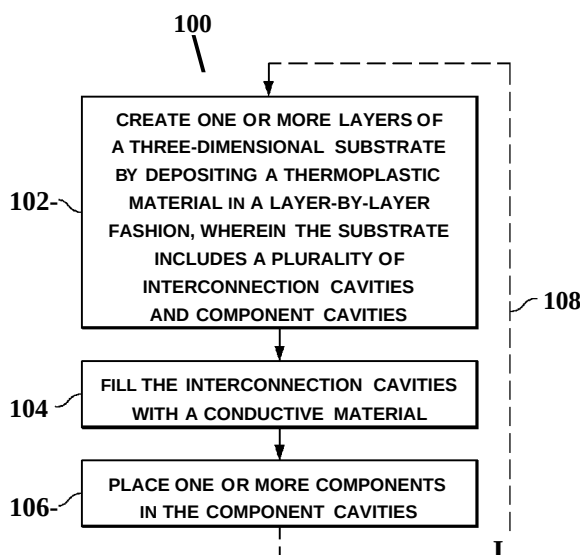


FIG. 1

(57) **Abstract:** The present invention provides a system and method for making a three-dimensional electronic, electromagnetic or electromechanical component/device by: (1) creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities; (2) filling the interconnection cavities with a conductive material; and (3) placing one or more components in the component cavities.



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**EXTRUSION-BASED ADDITIVE MANUFACTURING SYSTEM FOR 3D
STRUCTURAL ELECTRONIC, ELECTROMAGNETIC AND
ELECTROMECHANICAL COMPONENTS/DEVICES**

Field of Invention

The present invention relates in general to the manufacture of electronic, electromagnetic and electromechanical components and devices, and more particularly to multiple material fabrication using an extrusion-based additive manufacturing system.

5 Background Art

Without limiting the scope of the invention, its background is described in connection with methods for manufacturing 3D objects and structures, more specifically 3D structural electronic, electromagnetic and electromechanical components and devices.

U.S. Patent No. 5,121,329 issued to Crump (1992) discloses an apparatus
10 incorporating a movable dispensing head provided with a supply of material which solidifies at a predetermined temperature, and a base member, which are moved relative to each other along "X," "Y," and "Z" axes in a predetermined pattern to create three-dimensional objects by building up material discharged from the dispensing head onto the base member at a controlled rate. The apparatus is preferably computer driven in a process utilizing computer
15 aided design (CAD) and computer-aided manufacturing (CAM) software to generate drive signals for controlled movement of the dispensing head and base member as material is being dispensed. Three-dimensional objects may be produced by depositing repeated layers of solidifying material until the shape is formed. Any material, such as self-hardening waxes, thermoplastic resins, molten metals, two-part epoxies, foaming plastics, and glass, which
20 adheres to the previous layer with an adequate bond upon solidification, may be utilized and considered suitable for the process. Each layer base is defined by the previous layer, and each layer thickness is defined and closely controlled by the height at which the tip of the dispensing head is positioned above the preceding layer.

Summary of Invention

25 The present invention describes an extrusion-based additive manufacturing system for 3D structural electronics that uses an innovative manufacturing process whereby multiple technologies are integrated into a single apparatus, device or machine to produce multi-

material, heterogeneous, electronic structures exhibiting non-conventional component placement and sufficient mechanical properties.

The present invention provides a method for making a three-dimensional electronic, electromagnetic or electromechanical component/device by: (1) creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities; (2) filling the interconnection cavities with a conductive material; and (3) placing one or more electronic components in the component cavities. The process can be repeated to create additional layers of the three-dimensional substrate. The present invention also provides a three-dimensional electronic, electromagnetic or electromechanical component/device made by the foregoing method.

In addition, the present invention provides a system for making a three-dimensional electronic, electromagnetic or electromechanical component/device that includes a three-dimensional printing device that creates one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities. A first machine that fills the interconnection cavities with a conductive material. A component placement machine that places one or more components in the component cavities. The system may also include a slide, a conveyor or a robotic device that transports the three-dimensional substrate to each machine or sub-system.

Moreover, the present invention provides a three-dimensional electronic, electromagnetic or electromechanical component/device made by a method comprising the steps of (a) creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities, (b) filling the interconnection cavities with a conductive material, and (c) placing one or more components in the component cavities.

For a more complete understanding of the features and advantages of the present invention, reference is now made to the detailed description of the invention along with the accompanying figures and in which:

FIGURE 1 is a flow chart of a method for making a three-dimensional electronic, electromagnetic or electromechanical component/device in accordance with one embodiment of the present invention;

FIGURE 2 is a flow chart of a method for making a three-dimensional electronic, electromagnetic or electromechanical component/device in accordance with another embodiment of the present invention;

FIGURE 3 is a flow chart of method for making a three-dimensional electronic,
5 electromagnetic or electromechanical component/device in accordance with another embodiment of the present invention;

FIGURES 4A-4C show FDM-manufactured substrates with laser cut features demonstrating the feasibility of producing interconnection channels and component cavities with laser technologies in accordance with the present invention;

10 FIGURES 5A-5C show a broadband anti-reflection grating and FIGURE 5D shows a plot of the structure's performance in terms of electromagnetic reflectance, transmittance and conservation in accordance with various steps of the present invention;

FIGURE 6A shows a CAD model for a scaled UAV wing and FIGURES 6B-6D show the scaled UAV wing fabricated with an FDM machine in accordance with various steps of
15 the present invention;

FIGURES 7A and 7B show a circuit part manufactured with the first two steps of the present invention;

FIGURE 8 shows a component/device manufactured using the method in accordance with one embodiment of the present invention; and

20 FIGURES 9A-9D show an example of an extrusion-based additive manufacturing system for 3D structural electronic, electromagnetic and electromechanical components/devices in accordance with the present invention.

Description of the Invention

25 While the making and using of various embodiments of the present invention are discussed in detail below, it should be appreciated that the present invention provides many applicable inventive concepts that can be embodied in a wide variety of specific contexts. The specific embodiments discussed herein are merely illustrative of specific ways to make and use the invention and do not delimit the scope of the invention.

To facilitate the understanding of this invention, a number of terms are defined below.
30 Terms defined herein have meanings as commonly understood by a person of ordinary skill

in the areas relevant to the present invention. Terms such as "a", "an," and "the" are not intended to refer to only a singular entity, but include the general class of which a specific example may be used for illustration. The terminology herein is used to describe specific embodiments of the invention, but their usage does not delimit the invention, except as outlined in the claims.

One embodiment of the present invention provides an extrusion-based additive manufacturing system for 3D structural electronic, electromagnetic and electromechanical components/devices that utilizes fused deposition modeling (FDM), pick and place technology, computer numerical control (CNC) machining to develop an automated process that innovatively fabricates multi-material, heterogeneous, electronic, electromagnetic or electromechanical components/structures/devices without requiring assembly and exhibiting non-conventional component placement and sufficient mechanical properties and other material properties for the application. Some potentially relevant mechanical and material properties that may be required for the functional product may include impact resistance, elastic modulus, Poisson's ratio, flexural modulus and strength, tensile strength, creep, fatigue endurance, dielectric strength, dielectric constant, dissipation factor, thermal conductivity, deflection temperature, chemical resistivity, and water absorptivity. Additional processes can also be used as described below.

Access to individual layers while a 3D object is additively fabricated as described in the present invention allows for the integration of other complementary technologies to produce multi-material and multi-functional structures and devices. Additive Manufacturing (AM) has been used in a hybrid stereolithography (SL) and direct write (DW) system that successfully fabricated a LM 555 circuit [5, 6, 8, 9].

Fused deposition modeling (FDM) and direct-write, or direct print, technologies are used in the extrusion-based additive manufacturing system for fabricating 3D structural electronics, electromagnetic and electromechanical components/structures/devices. Electronic component placement in three-dimensions - different from the conventional planar placement in printed circuit board (PCB) arrangements - efficiently utilizes space and materials to satisfy mechanical and electrical design requirements of electronic, electromagnetic or electromechanical components/devices. Included in the new manufacturing process of the present invention is a subtractive manufacturing method (micro-machining) for the AM-fabricated substrate, which in the case of conventional FDM,

is an extruded thermoplastic material. Tests conducted have proven the successful CNC micro-machining of interconnection channels as small as 230 μm . Laser ablation tests have also been performed and show greater resolutions which may not be possible with current CNC micro-machining. Attributes of parts produced by this new invention are applicable in the electronics, electromechanical and biomedical industries.

Although widely used, electronic components housed on conventional PCB arrangements are not able to withstand more than minimal physical loads. In addition, mechanical and electrical designs are often conflicted as both cannot be realized with the planar layout that PCBs provide. The present invention, extrusion-based additive manufacturing system for 3D structural electronic, electromagnetic and electromechanical components/devices, addresses both these issues as: 1) parts are fabricated in a layered fashion wherein electronic components can be placed anywhere within a complex 3D part thus resulting in the simultaneous fulfillment of mechanical and electrical design requirements; and 2) parts can be designed and fabricated to possess multi-functions, such as the capability to provide impact resistance and substantial structural support by including stress reducing features (e.g., arches, trusses, filets, etc.) as well as intelligence through the integrated electronics, electromagnetic structures (e.g., gratings, transmission lines, filters, etc.) or electromechanical structures (e.g., actuators, gauges, mechanical sensors, etc.). Moreover, component and interconnection cavities do not require chemical cleansing as in the case of stereolithography wherein solvents are used to remove uncured photopolymer. This cleaning process is described in [4, 5, 6, 7, 8, 9, 10]. Residual photopolymer and solvent are both detrimental to the quality and reliability of electronic circuits.

One major drawback of a previously developed stereolithography/direct-write hybrid system with the capability of producing 3D electronic, electromagnetic and electromechanical components/devices is that the substrate material typically does not offer sufficient mechanical, thermal and electrical properties. Another limitation of prior systems is the 3D electronics are not impact resistant as parts tend to shatter when dropped. Moreover, the liquid resins used in stereolithography present problems during fabrication because the part and interconnection cavities have to be cleaned before components and conductive material can be embedded within the cavities. Further, once the components are inserted into the substrate and the conductive traces are added, the build may continue, causing the stereolithography liquid resin to possibly contaminate the inserted components and conductive traces, and require subsequent cleaning and removal of unreacted resin from

the final part. These issues can negatively impact the reliability of the resulting components/devices. Conversely, the extrusion-based additive manufacturing system for 3D structural electronics uses a thermoplastic substrate to mitigate these deficiencies.

Manufacture of 3D structural electronics has proven difficult with conventional manufacturing methods. Additive manufacturing provides the unique opportunity to access individual layers if process interruption is achieved. The present invention allows the fused deposition modeling (FDM) process to be interrupted so that electronic components or thermal management components can be embedded. FDM technology has not been used for structural electronics due to the lack of resolution required for electronic circuitry. It is expected that, as the use of additive processes for 3D electronics fabrication grows, the requirements for higher component and trace density will also grow. FDM is unable to compete with traditional PCB technologies in terms of trace density. Furthermore, many of the latest integrated circuits have geometries (e.g., pin pitch) that require a resolution greater than can be achieved with current FDM technology. The present invention solves the FDM resolution issue by employing subtractive manufacturing methods that are intermittently used during the additive manufacturing process to provide high resolution and accurate features. These subtractive manufacturing processes may include a micro-machining machine, a CNC micro-machining machine, a micro electrical discharge machining machine, an electrochemical machining machine, a direct write proton micro-machining machine, a laser ablation machine, a radiative source, an ultrasonic cutting machine, a hot wire cutting machine, a waterjet machine, an etching machine, a deep reactive ion etching machine, a plasma etching machine, a crystal orientation dependent etching machine, a wet bulk micromachining machine, a UV-lithography or X-ray lithography (LIGA) machine, a hot embossing lithography machine, a precision mechanical sawing machine, a chemically assisted ion milling machine, a sand blasting machine, a cutting machine, or other suitable systems. CNC micromachining can achieve interconnection channels as small as $230\text{ }\mu\text{m}$ while laser micro-machining can be used to produce relatively smaller features.

The extrusion-based additive manufacturing system for 3D structural electronics addresses the limitations of the planar arrangement in a conventional PCB. Non-conventional placement of electronic components in a complex 3D part will enable the evolution of circuitry design. That is, parts will be limited by designs rather than manufacturing capabilities as is the current state-of-the-art. PCBs use a substrate that provides mechanical stability for component interconnections and require a housing to

provide structural support for the entire electronic, electromagnetic or electromechanical component/device. The present invention provides components/devices with structural support without having to use a housing unless such a housing is desired.

The extrusion-based additive manufacturing system for 3D structural electronics has applications in the electronics industry as it promises to dramatically reduce manufacturing cost by, for example, eliminating the requirement of always having a housing to provide structural support. Government agencies, such as the Department of Defense, can use the present invention in a wide variety of applications including, but not limited to: 1) unmanned aerial systems (UASs) or unmanned aerial vehicles (UAVs) by providing aerodynamic parts with embedded sensors, communications and electronics within structural components or by directly fabricating onto UAS and UAV surfaces; 2) customized, mission-specific disposable electronics; 3) truly 3D antennas and photonic devices that improve communications; 4) replacement components for virtually any electronic system on a naval vessel; 5) custom fit sailor-borne electronics and communications systems; and 6) disposable floating depth-specific sensor systems. The invention can also be used in structural health monitoring, where 3D electronics are expected to play an important role in the future. This invention will allow real-time nondestructive monitoring of structural parts where sensors can be strategically placed in a complex part, which is very difficult to do with current manufacturing processes.

Now referring to FIGURE 1, a flow chart of a method 100 for making a three-dimensional electronic, electromagnetic or electromechanical component/device in accordance with one embodiment of the present invention is shown. One or more layers of a three-dimensional substrate is/are created by depositing a substrate material in a layer-by-layer fashion in block 102. The substrate material may include a thermoplastic material as is typically used in FDM, or alternatively may include another polymer material, a ceramic material, a metallic material, a mineral material, a glass ceramic material, a semi-conductor material, a nanomaterial, a biomaterial, an organic material, an inorganic material, or any combination thereof. The substrate includes a plurality of interconnection cavities and component cavities. The thermoplastic material can be a material currently used commercially in FDM, such as acrylonitrile butadiene styrene (ABS), ABSi, ABSplus, ABS-M30, ABS-M30i, polycarbonate (PC), PC-ABS, PC-ISO, polyphenylsulfone (PPSF/PPSU), ULTEM 9085, or other material available from the FDM manufacturer; or alternatively, virtually any extrudable material such as poly(methyl methacrylate) (PMMA),

polypropylene, polyolefm, LL-PE, HDPE, polyvinyl acetate, polyester, polyamides, nylon, polyimides, polyketone, polyether ethyl ketone (PEEK), polybutadiene, polylactic acid, polycaprolactone, polyethylene terephthalate, liquid crystalline polymer (LCP), polystyrene, polyvinyl chloride, polyfluoroethylene, polydifluoroethylene, polytetrafluoroethylene, ZEONEX RS420, Eccostock HIK-TPO, co-polymers and block co-polymers of the previous, or any other suitable material and any combination thereof. Moreover, the one or more layers can be deposited using a three-dimensional printing process, a fused deposition modeling process or other suitable process. The interconnection cavities may include an interconnection channel, a pin cavity and/or a via. The portion of the substrate can be removed using a micro-machining process, a laser ablation process or other suitable process. The interconnection cavities are filled with a conductive material in block 104. The conductive material can be a metal, a metal alloy, an ink containing conductive particles (e.g., silver particles), a conductive polymer, a wire or other suitable material. Note that filling the interconnections cavities can be done by inserting, placing or otherwise causing the conductive material (e.g., a liquid, a paste, a wire-bond, a filament, a solid, etc.) to be within the interconnection cavity. The interconnection cavities can be filled using a direct-write microdispensing process, a direct-print microdispensing process, a fused deposition modeling head, another extrusion-based deposition system, an inkjet dispensing system, a spray machine, a wire bonding machine, a solder machine, a photolithographic technique, an electrodeposition machine, a damascene process, a rotogravure machine, an electro sputtering machine or other suitable process. Additionally, the interconnection cavities may be filled by physically embedding electrical conductors. Subsequently, an ultrasonic staking machine may be used to secure the electrical conductor or components.

One or more components are placed (automatically, semi-automatically, manually, etc.) in the component cavities in block 106. The electronic components may include an electronic component (e.g., an integrated circuit, a resistor, a capacitor, an inductor, a transistor, a thermistor, a thyristor, a sensor, a processor, a memory, an interface device, a display, a power source, an energy conversion device or an antenna), an electrostatic component, a pneumatic component, an electroacoustic component, a microelectromechanical system (MEMS), a biomedical component, an electrochemical component, an electromechanical component, an electromagnetic component, a mechanical component, a metamaterial component, an optical component, a photonic component, a thermal component, a thermal management component, or any other desired component. The

electronic components can be placed by hand or by using a component placement machine, such as a pick and place machine, a robotic process or other automated component placement technology. In some embodiments, the conductive material is cured. The conductive material can be cured using a laser, an Ohmic curing process, an inductive curing process, a radiation curing process, a thermal curing process, an electric polarization process or a magnetic polarization process or other suitable process. Several of these methods of curing are described in [8, 9, 10, 11] as examples. Moreover, the curing can be localized or directed to a specific conductive material rather than exposing the entire structure to the extremes necessary for the curing. Localized, high energy fluxes will also ensure an energy efficient process. Note that the curing step can be eliminated whenever a self-curing conductive material is used. As indicated by line 108, the process (blocks 102, 104 and/or 106) can be repeated to create additional layers of the three-dimensional substrate. The resulting three-dimensional substrate provides structural support for the electronic components, and may or may not require a housing for structural support. The three-dimensional substrate may include one or more arches, trusses, filets or other stress reducing features.

The plurality of interconnection cavities and component cavities within the substrate can be created by removing a portion of the substrate using a micro-machining machine, a CNC micro-machining machine, a micro electrical discharge machining machine, an electrochemical machining machine, a direct write proton micro-machining machine, a laser ablation machine, a radiative source, an ultrasonic cutting machine, a hot wire cutting machine, a waterjet machine, an etching machine, a deep reactive ion etching machine, a plasma etching machine, a crystal orientation dependent etching machine, a wet bulk micromachining machine, a UV-lithography or X-ray lithography (LIGA) machine, a hot embossing lithography machine, a precision mechanical sawing machine, a chemically assisted ion milling machine, a sand blasting machine, a cutting machine, or other suitable systems. As an example, FIGURES 4A-4C show FDM-manufactured substrates with laser cut features demonstrating the feasibility of producing interconnection channels and component cavities with laser technologies. In addition, a portion of the substrate can be removed for a diffraction grating, an electromagnetically responsive structure, a cooling channel, a vent or any other desired structure. As an example, FIGURES 5A-5C show a broadband anti-reflection grating and FIGURE 5D shows a plot of the structure's performance in terms of electromagnetic reflectance, transmittance and conservation. Moreover, the process may also include the step of depositing a thermally conductive

material, a ceramic material, a dielectric material, a magnetic material, a piezoelectric material, an insulating material, an elastomer, a wax, a resin, an epoxy, a plastic material, a glass or any combination thereof on the substrate. The three-dimensional substrate can be transported to the various machines using a slide, a conveyor, a robotic device or other suitable transport mechanism.

In another embodiment, cavities are not formed in the substrate. Instead, the components and/or conductive materials are deposited or inserted directly on a layer of the substrate material. One or more additional layers of substrate material are then deposited on top of the components and/or conductive materials. As an example, FIGURES 6A shows a CAD model for a scaled UAV wing and FIGURES 6B-6D show the scaled UAV wing fabricated with an FDM machine. Cavities for several discrete components such as capacitors, resistors, inductors, and interconnection pins were designed with SolidWorks. As in [12], embedded electronic components were inserted into their respective cavities; however, the conductive inks were printed directly on the conformal substrate without the need for interconnection cavities.

Referring now to FIGURE 2, a flow chart of method 200 for making a three-dimensional electronic, electromagnetic or electromechanical component/device in accordance with another embodiment of the present invention is shown. The process starts in block 202. If high resolution features are required, as determined in decision block 204, the substrate material is deposited using FDM in block 206, substrate material is selectively removed to produce high resolution features in block 208, and the electronic component cavities are populated and the interconnection channels are filled in block 210. If, however, high resolution features are not required, as determined in decision block 204, the electronic substrate including low resolution features is fabricated using FDM in block 212, and the electronic component cavities are populated and the interconnection channels are filled in block 210. If post-processing is required for conductive media, as determined in decision block 214, the conductive media is post-processed in block 216. Thereafter or if post-processing is not required for conductive media, as determined in decision block 214, the process repeats by looping back to decision block 204 whenever additional layers with embedded electronics are required, as determined in decision block 218. If, however, additional layers are not required, as determined in decision block 218, the process ends in block 220.

Now referring to FIGURE 3, a flow chart of method 300 for making a three-dimensional electronic, electromagnetic or electromechanical component/device in accordance with another embodiment of the present invention is shown. The FDM phase 302 includes the step of depositing a substrate material (e.g., a thermoplastic material) in a layer-by-layer fashion to function as: 1) a substrate for conductive media; and 2) structural support for the device. Materials development studies have been conducted to adopt new thermoplastics (e.g., PMMA [13], polycaprolactone [14], polypropylene, ZEONEX RS420, Eccostock HIK-TPO) for the FDM process 302 that will enable the fabrication of devices whose attributes find applications in the electronic and biomedical industries. Some of these materials exhibit improved properties relevant to the application. As an example of a biomedical material, PMMA is used as a bone cement due to its relatively high tensile strength (60 MPa) and high softening temperature (125 °C). ZEONEX RS420 is an example of a substrate material for use in the electronic industry due to its low dielectric tangent loss (0.0002 at 1MHz) and dielectric constant (2.3 at 1MHz). After a specified number of layers have been deposited, a pneumatic stage 312 (or other transport mechanism) will transport the workpiece to the micro-machining phase 304. Between all phases, the pneumatic slide 312 is used to transport the work piece. The feature resolution achieved by FDM is not sufficient for electronic circuitry and therefore micro-machining 304 - either by laser, CNC or other suitable process - is required. In the micromachining phase 304, the substrate is machined to produce features (e.g., FIGURES 7A and 7B) that include interconnection channels, component cavities, and vias or serve as a finishing process to achieve the required resolution and accuracy. Once machined, the workpiece is delivered to the DW phase 306 where conductive media (e.g., silver ink or other suitable material) is dispensed into the interconnection channels and pin locations. Electronic components (e.g., microprocessors, capacitors, resistors, etc.) are placed in their respective cavities by hand or by utilizing pick and place technology 308 or other similar automated component placement technology. One manufacturing cycle is completed with the processing of the conductive media. That is, the silver ink is cured with the use of a laser 310 or other suitable process. In addition, the silver particles within the ink are sintered by using laser energy. The manufacturing process 300 is repeated until a complete part, with embedded components, is produced. Note that machines may not be required to perform every portion of the manufacturing process 300.

Note that the previously described methods can be implemented using a computer program embodied on a non-transitory computer readable medium wherein the steps are performed using one or more code segments.

Referring now to FIGURES 7A and 7B, a circuit part 700 manufactured with the first two steps of the present invention is shown. More specifically, FIGURE 7A is a photograph of the circuit part 700, and FIGURE 7B is an enlarged portion of circuit part 700. The circuit part or three-dimensional electronic, electromagnetic or electromechanical component/device 700 includes a substrate 702 with a plurality of interconnection cavities 704 and electronic component cavities 706 within the substrate.

Now referring to FIGURE 8, a component/device manufactured using the method in accordance with one embodiment of the present invention is shown. This is a substrate that was machined with a CNC router, interconnection channels filled with conductive media, and electronic components have been placed into their corresponding cavities.

Referring now to FIGURES 9A-9D, an example of an extrusion-based additive manufacturing system 900 for 3D structural electronic, electromagnetic or electromechanical components/devices in accordance with the present invention is shown. More specifically, FIGURES 9A-9B shows a partially completed system 900, FIGURE 9C shows a FDM tooling head, and FIGURE 9D shows a DW microdispensing head. The system 900 for making a three-dimensional electronic, electromagnetic or electromechanical component/device includes a fused deposition modeling machine 902 that creates one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, a micro-machining machine or a laser ablation machine 904 that removes a portion of the substrate to form a plurality of interconnection cavities and electronic component cavities within the substrate, a direct-write or direct-print microdispensing machine 906 that fills the interconnection cavities with a conductive material, and a pick and place machine 908 that places one or more electronic components in the electronic component cavities. The laser 904 can also cure the conductive material. The system also includes a pneumatic slide 910 that transports the three-dimensional substrate to each machine or sub-system. All of the machines can be integrated into a single machine or similar manufacturing system or process.

As previously mentioned, parts produced by this invention will be used in various applications such as: 1) unmanned aerial systems (UASs) and unmaned areial vehicles

(UAVs) by providing aerodynamic parts with embedded sensors, communications and electronics within structural components or by directly fabricating onto UAS and UAV surfaces; 2) customized, mission-specific disposable electronics; 3) truly 3D antennas and photonic devices that improve communications; 4) replacement components for virtually any electronic system on a naval vessel; 5) custom fit sailor-borne electronics and communications systems; and 6) disposable floating depth-specific sensor systems; 7) biomedical devices; and 8) metamaterial structures.

It may be understood that particular embodiments described herein are shown by way of illustration and not as limitations of the invention. The principal features of this invention can be employed in various embodiments without departing from the scope of the invention. Those skilled in the art will recognize, or be able to ascertain using no more than routine experimentation, numerous equivalents to the specific procedures described herein. Such equivalents are considered to be within the scope of this invention and are covered by the claims.

All publications, patents and patent applications mentioned in the specification are indicative of the level of skill of those skilled in the art to which this invention pertains. All publications, patents and patent applications are herein incorporated by reference to the same extent as if each individual publication, patent or patent application was specifically and individually indicated to be incorporated by reference.

The use of the word "a" or "an" when used in conjunction with the term "comprising" in the claims and/or the specification may mean "one," but it is also consistent with the meaning of "one or more," "at least one," and "one or more than one." The use of the term "or" in the claims is used to mean "and/or" unless explicitly indicated to refer to alternatives only or the alternatives are mutually exclusive, although the disclosure supports a definition that refers to only alternatives and "and/or." Throughout this application, the term "about" is used to indicate that a value includes the inherent variation of error for the device, the method being employed to determine the value, or the variation that exists among the study subjects.

As used in this specification and claim(s), the words "comprising" (and any form of comprising, such as "comprise" and "comprises"), "having" (and any form of having, such as "have" and "has"), "including" (and any form of including, such as "includes" and "include") or "containing" (and any form of containing, such as "contains" and "contain") are inclusive or open-ended and do not exclude additional, unrecited elements or method steps.

The term "or combinations thereof" as used herein refers to all permutations and combinations of the listed items preceding the term. For example, "A, B, C, or combinations thereof" is intended to include at least one of: A, B, C, AB, AC, BC, or ABC, and if order is important in a particular context, also BA, CA, CB, CBA, BCA, ACB, BAC, or CAB.

5 Continuing with this example, expressly included are combinations that contain repeats of one or more item or term, such as BB, AAA, MB, BBC, AAABCCCC, CBBAAA, CABABB, and so forth. The skilled artisan will understand that typically there is no limit on the number of items or terms in any combination, unless otherwise apparent from the context.

10 All of the compositions and/or methods disclosed and claimed herein can be made and executed without undue experimentation in light of the present disclosure. While the compositions and methods of this invention have been described in terms of preferred embodiments, it may be apparent to those of skill in the art that variations may be applied to the compositions and/or methods and in the steps or in the sequence of steps of the method described herein without departing from the concept, spirit and scope of the invention. All
15 such similar substitutes and modifications apparent to those skilled in the art are deemed to be within the spirit, scope and concept of the invention as defined by the appended claims.

CLAIMS

1. A method of making a three-dimensional electronic, electromagnetic or electromechanical component/device comprising the steps of:

creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities;

filling the interconnection cavities with a conductive material; and

placing one or more components in the component cavities.

2. The method as recited in claim 1, further comprising the step of curing the conductive material.

3. The method as recited in claim 1, wherein the substrate material comprises a thermoplastic material, another polymer material, a ceramic material, a metallic material, a mineral material, a glass ceramic material, a semi-conductor material, a nanomaterial, a biomaterial, an organic material, an inorganic material or any combination thereof.

4. The method as recited in claim 3, wherein the thermoplastic material comprises acrylonitrile butadiene styrene (ABS), ABSi, ABSplus, ABS-M30, ABS-M30i, polycarbonate (PC), PC-ABS, PC-ISO, polyphenylsulfone (PPSF/PPSU), ULTEM 9085 or any combination thereof.

5. The method as recited in claim 3, wherein the another polymer material comprises poly(methyl methacrylate) (PMMA), polypropylene, polyolefin, LL-PE, HDPE, polyvinyl acetate, polyester, polyamides, nylon, polyimides, polyketone, polyether ethyl ketone (PEEK), polybutadiene, polylactic acid, polycaprolactone, polyethylene terephthalate, liquid crystalline polymer (LCP), polystyrene, polyvinyl chloride, polyfluoroethylene, polydifluoroethylene, polytetrafluoroethylene, ZEONEX RS420, Eccostock HIK-TPO, co-polymers and block co-polymers of the previous, or any combination thereof.

6. The method as recited in claim 1, wherein at least one of the plurality of interconnection cavities and component cavities within the substrate are created by removing a portion of the substrate.

7. The method as recited in claim 1, further comprising the step of removing a portion of the substrate for an electromagnetic structure, an electromechanical structure, a cooling channel or a vent.

8. The method as recited in claim 1, further comprising the step of depositing a thermally conductive material, a ceramic material, a dielectric material, a magnetic material, a piezoelectric material, an insulating material, an elastomer, a wax, a resin, an epoxy, a plastic material, a glass or any combination thereof on the substrate.
- 5 9. The method as recited in claim 1, further comprising the step of creating one or more additional layers of the three-dimensional substrate by depositing the substrate material in the layer-by-layer fashion.
10. The method as recited in claim 9, repeating the filling, placing and curing steps for the additional layers.
- 10 11. The method as recited in claim 1, wherein the one or more layers are deposited using a fused deposition modeling process.
12. The method as recited in claim 1, wherein the interconnection cavities comprise an interconnection channel, a pin cavity or a via.
13. The method as recited in claim 1, wherein the portion of the substrate is removed
15 using a micro-machining machine, a CNC micro-machining machine, a micro electrical discharge machining machine, an electrochemical machining machine, a direct write proton micro-machining machine, a laser ablation machine, a radiative source, an ultrasonic cutting machine, a hot wire cutting machine, a waterjet machine, an etching machine, a deep reactive ion etching machine, a plasma etching machine, a crystal orientation dependent etching
20 machine, a wet bulk micromachining machine, a UV-lithography or X-ray lithography (LIGA) machine, a hot embossing lithography machine, a precision mechanical sawing machine, a chemically assisted ion milling machine, a sand blasting machine, a cutting machine.
14. The method as recited in claim 1, wherein the conductive material comprises a metal,
25 a metal alloy, an ink containing conductive particles, a conductive polymer or a wire.
15. The method as recited in claim 1, wherein the interconnection cavities are filled with the conductive material using a direct-write microdispensing process, a direct-print microdispensing process, a fused deposition modeling head, another extrusion-based deposition system, an inkjet dispensing system, a spray machine, a wire bonding machine, a
30 solder machine, a photolithographic technique, an electrodeposition machine, a damascene

process, a rotogravure machine, an electro sputtering machine or by a physical embedding process.

16. The method as recited in claim 1, wherein the conductive material is cured using a laser, an Ohmic curing process, an inductive curing process, a radiation curing process, a thermal curing process, an electric polarization process or a magnetic polarization process.

17. The method as recited in claim 1, wherein the curing step is localized or directed to a specific conductive material.

18. The method as recited in claim 1, wherein the components comprise an electronic component, an electrostatic component, a pneumatic component, an electroacoustic component, a microelectromechanical system (MEMS), a biomedical component, an electrochemical component, an electromechanical component, an electromagnetic component, a mechanical component, a metamaterial component, an optical component, a photonic component, a thermal component or a thermal management component.

19. The method as recited in claim 18, wherein the electronic component comprises an integrated circuit, a resistor, a capacitor, an inductor, a transistor, a thermistor, a thyristor, a sensor, a processor, a memory, an interface device, a display, a power source, an energy conversion device or an antenna.

20. The method as recited in claim 1, wherein the components are placed by hand or using a component placement machine, wherein the component placement machine comprises a pick and place machine, a robotic process or other automated component placement technology.

21. The method as recited in claim 1, wherein the three-dimensional substrate provides structural support for the components.

22. The method as recited in claim 21, wherein the three-dimensional electronic, electromagnetic or electromechanical component/device does not require a housing for structural support.

23. The method as recited in claim 21, wherein the three-dimensional substrate includes one or more arches, trusses, filets or other stress reducing features.

24. A three-dimensional electronic, electromagnetic or electromechanical component/device made by a method comprising the steps of (a) creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion,

wherein the substrate includes a plurality of interconnection cavities and component cavities, (b) filling the interconnection cavities with a conductive material, and (c) placing one or more components in the component cavities.

25. The device made by the method as recited in claim 24, further comprising the step of
5 curing the conductive material.

26. The device made by the method as recited in claim 24, wherein the substrate material
comprises a thermoplastic material, another polymer material, a ceramic material, a metallic
material, a mineral material, a glass ceramic material, a semi-conductor material, a
nanomaterial, a biomaterial, an organic material, an inorganic material or any combination
10 thereof.

27. The device made by the method as recited in claim 26, wherein the thermoplastic
material comprises acrylonitrile butadiene styrene (ABS), ABSi, ABSplus, ABS-M30, ABS-
M30i, polycarbonate (PC), PC-ABS, PC-ISO, polyphenylsulfone (PPSF/PPSU), ULTEM
9085 or any combination thereof.

28. The device made by the method as recited in claim 26, wherein the another polymer
material comprises poly(methyl methacrylate) (PMMA), polypropylene, polyolefm, LL-PE,
HDPE, polyvinyl acetate, polyester, polyamides, nylon, polyimides, polyketone, polyether
ethyl ketone (PEEK), polybutadiene, polylactic acid, polycaprolactone, polyethylene
terephthalate, liquid crystalline polymer (LCP), polystyrene, polyvinyl chloride,
20 polyfluoroethylene, polydifluoroethylene, polytetrafluoroethylene, ZEONEX RS420,
Eccostock HIK-TPO, co-polymers and block co-polymers of the previous, or any
combination thereof.

29. The device made by the method as recited in claim 24, further comprising the step of
removing a portion of the substrate for an electromagnetic structure, an electromechanical
25 structure, a cooling channel or a vent.

30. The device made by the method as recited in claim 24, further comprising the step of
depositing a thermally conductive material, a ceramic material, a dielectric material, a
magnetic material, a piezoelectric material, an insulating material, an elastomer, a wax, a
resin, an epoxy, a plastic material, a glass or any combination thereof on the substrate.

31. The device made by the method as recited in claim 24, further comprising the step of creating one or more additional layers of the three-dimensional substrate by depositing the substrate material in the layer-by-layer fashion.

32. The device made by the method as recited in claim 31, repeating the filling, placing
5 and curing steps for the additional layers.

33. The device made by the method as recited in claim 24, wherein the one or more layers are deposited using a fused deposition modeling process.

34. The device made by the method as recited in claim 24, wherein the interconnection cavities comprise an interconnection channel, a pin cavity or a via.

10 35. The device made by the method as recited in claim 24, wherein the portion of the substrate is removed using a micro-machining machine, a CNC micro-machining machine, a micro electrical discharge machining machine, an electrochemical machining machine, a direct write proton micro-machining machine, a laser ablation machine, a radiative source, an ultrasonic cutting machine, a hot wire cutting machine, a waterjet machine, an etching
15 machine, a deep reactive ion etching machine, a plasma etching machine, a crystal orientation dependent etching machine, a wet bulk micromachining machine, a UV-lithography or X-ray lithography (LIGA) machine, a hot embossing lithography machine, a precision mechanical sawing machine, a chemically assisted ion milling machine, a sand blasting machine, a cutting machine.

20 36. The device made by the method as recited in claim 24, wherein the conductive material comprises a metal, a metal alloy, an ink containing conductive particles, a conductive polymer or a wire.

37. The device made by the method as recited in claim 24, wherein the interconnection cavities are filled with the conductive material using a direct-write microdispensing process,
25 a direct-print microdispensing process, a fused deposition modeling head, another extrusion-based deposition system, an inkjet dispensing system, a spray machine, a wire bonding machine, a solder machine, a photolithographic technique, an electrodeposition machine, a damascene process, a rotogravure machine, an electro sputtering machine or by a physical embedding process.

30 38. The device made by the method as recited in claim 24, wherein the conductive material is cured using a laser, an Ohmic curing process, an inductive curing process, a

radiation curing process, a thermal curing process, an electric polarization process or a magnetic polarization process.

39. The device made by the method as recited in claim 24, wherein the curing step is localized or directed to a specific conductive material.

5 40. The device made by the method as recited in claim 24, wherein the components comprise an electronic component, an electrostatic component, a pneumatic component, an electroacoustic component, a microelectromechanical system (MEMS), a biomedical component, an electrochemical component, an electromechanical component, an electromagnetic component, a mechanical component, a metamaterial component, an optical
10 component, a photonic component, a thermal component or a thermal management component.

41. The device made by the method as recited in claim 40, wherein the electronic component comprises an integrated circuit, a resistor, a capacitor, an inductor, a transistor, a thermistor, a thyristor, a sensor, a processor, a memory, an interface device, a display, a
15 power source, an energy conversion device or an antenna.

42. The device made by the method as recited in claim 24, wherein the components are placed by hand or using a component placement machine, wherein the component placement machine comprises a pick and place machine, a robotic process or other automated component placement technology.

20 43. The device made by the method as recited in claim 24, wherein the three-dimensional substrate provides structural support for the components.

44. The device made by the method as recited in claim 24, wherein the three-dimensional electronic, electromagnetic or electromechanical component/device does not require a housing for structural support.

25 45. The device made by the method as recited in claim 44, wherein the three-dimensional substrate includes one or more arches, trusses, filets or other stress reducing features.

46. A system for making a three-dimensional electronic, electromagnetic or electromechanical component/device comprising.

a three-dimensional printing device that creates one or more layers of a three-
30 dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a plurality of interconnection cavities and component cavities;

a first machine that fills the interconnection cavities with a conductive material; and
a component placement machine that places one or more components in the
component cavities.

47. The system as recited in claim 46, further comprising a second machine that cures the
5 conductive material.

48. The system as recited in claim 46, wherein the substrate material comprises a
thermoplastic material, another polymer material, a ceramic material, a metallic material, a
mineral material, a glass ceramic material, a semi-conductor material, a nanomaterial, a
biomaterial, an organic material, an inorganic material or any combination thereof.

10 49. The system as recited in claim 48, wherein the thermoplastic material comprises
acrylonitrile butadiene styrene (ABS), ABSi, ABSplus, ABS-M30, ABS-M30i,
polycarbonate (PC), PC-ABS, PC-ISO, polyphenylsulfone (PPSF/PPSU), ULTEM 9085 or
any combination thereof.

50. The system as recited in claim 48, wherein the another polymer material comprises
15 poly(methyl methacrylate) (PMMA), polypropylene, polyolefin, LL-PE, HDPE, polyvinyl
acetate, polyester, polyamides, nylon, polyimides, polyketone, polyether ethyl ketone
(PEEK), polybutadiene, polylactic acid, polycaprolactone, polyethylene terephthalate, liquid
crystalline polymer (LCP), polystyrene, polyvinyl chloride, polyfluoroethylene,
polydifluoroethylene, polytetrafluoroethylene, ZEONEX RS420, Eccostock HIK-TPO, co-
20 polymers and block co-polymers of the previous, or any combination thereof.

51. The system as recited in claim 46, wherein:

the three-dimensional printing device comprises a fused deposition modeling
machine; and

the first machine comprises a direct-write microdispensing process, a direct-print
25 microdispensing process, a fused deposition modeling head, another extrusion-based
deposition system, an inkjet dispensing system, a spray machine, a wire bonding machine, a
solder machine, a photolithographic technique, an electrodeposition machine, a damascene
process, a rotogravure machine, an electro sputtering machine or by a physical embedding
process.

30 52. The system as recited in claim 46, wherein the second machine comprises a laser, an
Ohmic curing machine, an inductive curing machine, a radiation curing machine, a thermal
curing machine, an electric polarization machine or a magnetic polarization machine.

53. The system as recited in claim 46, further comprising a micro-machining machine, a CNC micro-machining machine, a micro electrical discharge machining machine, an electrochemical machining machine, a direct write proton micro-machining machine, a laser ablation machine, a radiative source, an ultrasonic cutting machine, a hot wire cutting machine, a waterjet machine, an etching machine, a deep reactive ion etching machine, a plasma etching machine, a crystal orientation dependent etching machine, a wet bulk micromachining machine, a UV-lithography or X-ray lithography (LIGA) machine, a hot embossing lithography machine, a precision mechanical sawing machine, a chemically assisted ion milling machine, a sand blasting machine, a cutting machine.
54. The system as recited in claim 53, wherein another portion of the substrate for an electromagnetic structure, an electromechanical structure, a cooling channel or a vent.
55. The system as recited in claim 46, further comprising a slide, a conveyor or a robotic device that transports the three-dimensional substrate to each machine.
56. The system as recited in claim 46, wherein all of the machines are integrated into a single machine.
57. The system as recited in claim 46, wherein the first machine further deposits a thermally conductive material, a ceramic material, a dielectric material, a magnetic material, a piezoelectric material, an insulating material, an elastomer, a wax, a resin, an epoxy, a plastic material, a glass or any combination thereof on the substrate.
58. The system as recited in claim 46, wherein the interconnection cavities comprise an interconnection channel, a pin cavity or a via.
59. The system as recited in claim 46, wherein the conductive material comprises a metal, a metal alloy, an ink containing conductive particles, a conductive polymer or a wire.
60. The system as recited in claim 46, wherein the curing step is localized or directed to a specific conductive material.
61. The system as recited in claim 46, wherein the components comprise an electronic component, an electrostatic component, a pneumatic component, an electroacoustic component, a microelectromechanical system (MEMS), a biomedical component, an electrochemical component, an electromechanical component, an electromagnetic component, a mechanical component, a metamaterial component, an optical component, a photonic component, a thermal component or a thermal management component.

62. The system as recited in claim 61, wherein the electronic component comprises an integrated circuit, a resistor, a capacitor, an inductor, a transistor, a thermistor, a thyristor, a sensor, a processor, a memory, an interface device, a display, a power source, an energy conversion device or an antenna.

5 63. A computer program embodied on a non-transitory computer readable medium for making a three-dimensional electronic, electromagnetic or electromechanical component/device, the computer program comprising:

a code segment for creating one or more layers of a three-dimensional substrate by depositing a substrate material in a layer-by-layer fashion, wherein the substrate includes a
10 plurality of interconnection cavities and component cavities;

a code segment for filling the interconnection cavities with a conductive material; and

a code segment for placing one or more electronic components in the electronic component cavities.

64. The computer program as recited in claim 63, further comprising a code segment for
15 curing the conductive material.

65. The computer program as recited in claim 63, wherein the substrate material comprises a thermoplastic material, another polymer material, a ceramic material, a metallic material, a mineral material, a glass ceramic material, a semi-conductor material, a nanomaterial, a biomaterial, an organic material, an inorganic material or any combination
20 thereof.

66. The computer program as recited in claim 63, wherein at least one of the plurality of interconnection cavities and component cavities within the substrate are created by removing a portion of the substrate.

67. The computer program as recited in claim 63, further comprising a code segment for
25 removing a portion of the substrate for an electromagnetic structure, an electromechanical structure, a cooling channel or a vent.

68. The computer program as recited in claim 63, further comprising a code segment for depositing a thermally conductive material, a ceramic material, a dielectric material, a magnetic material, a piezoelectric material, an insulating material, an elastomer, a wax, a
30 resin, an epoxy, a plastic material or a plastic material, a glass or any combination thereof on the substrate.

69. The computer program as recited in claim 63, further comprising a code segment for creating one or more additional layers of the three-dimensional substrate by depositing the substrate material in the layer-by-layer fashion.

70. The computer program as recited in claim 69, further comprising a code segment for
5 repeating the filling, placing and curing steps for the additional layers.

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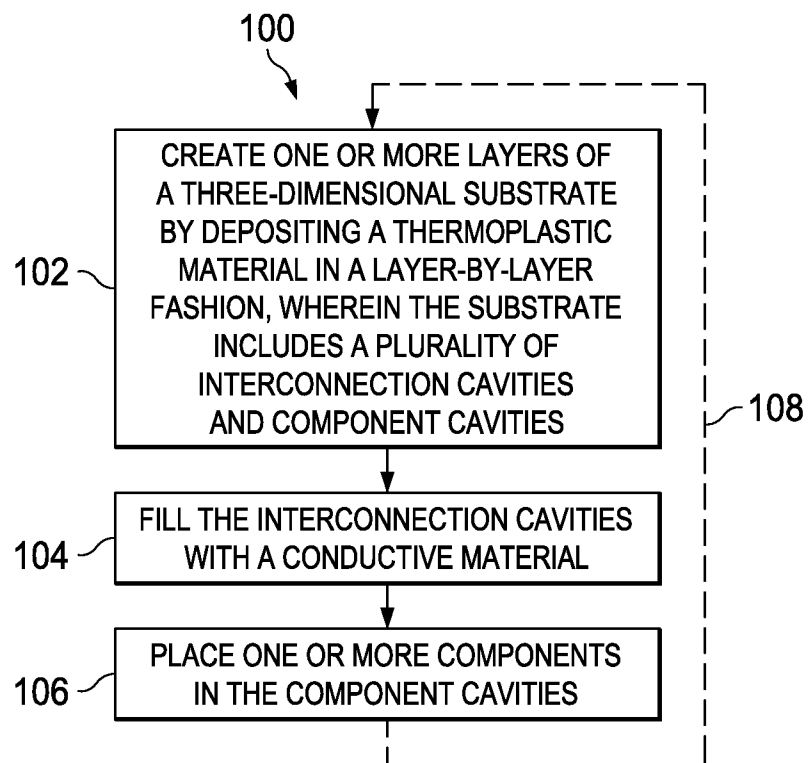


FIG. 1

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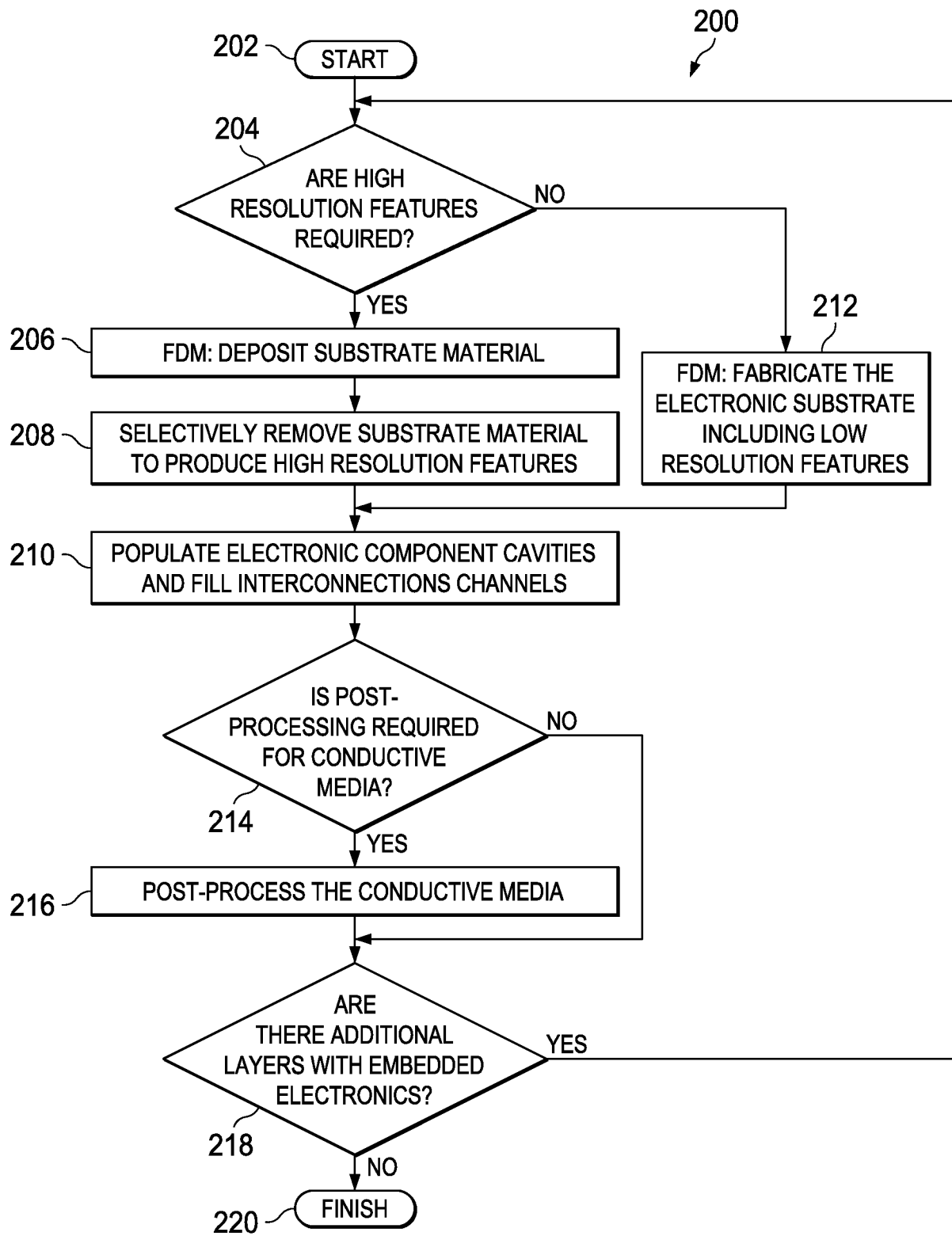


FIG. 2

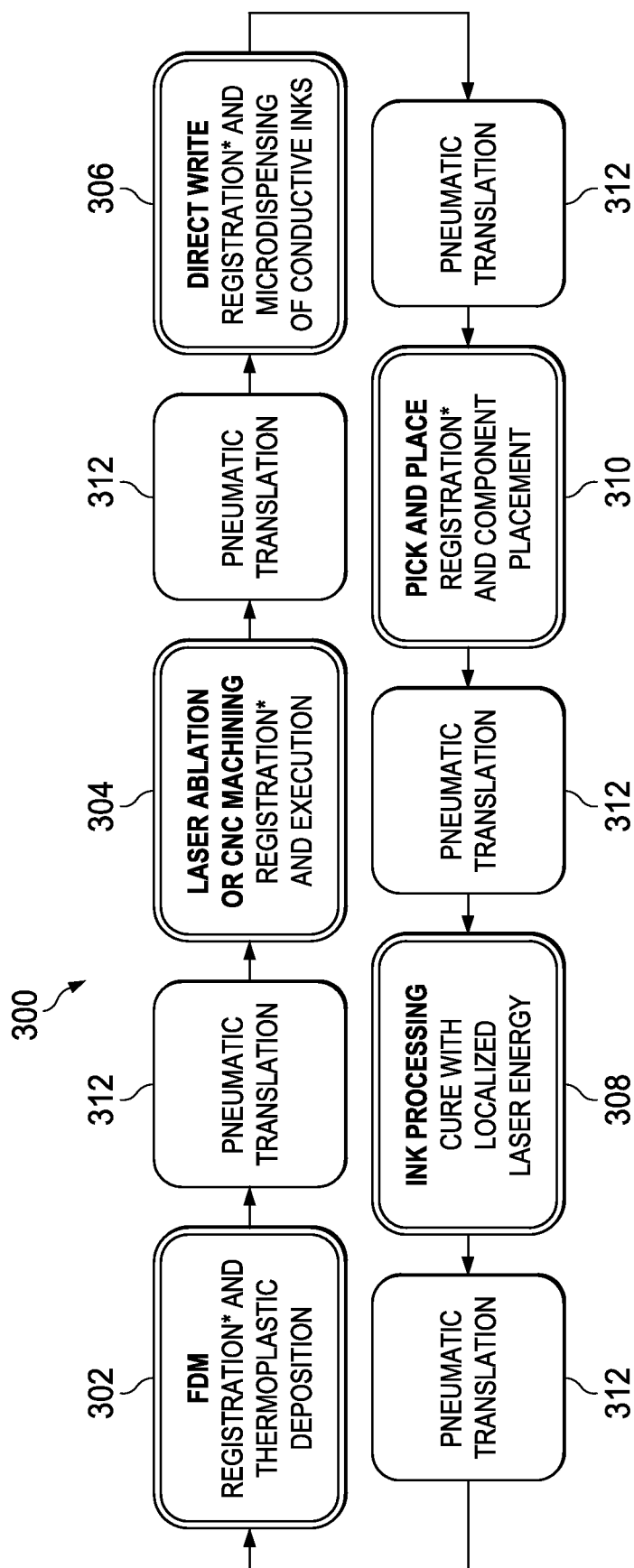


FIG. 3

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FIG. 4A

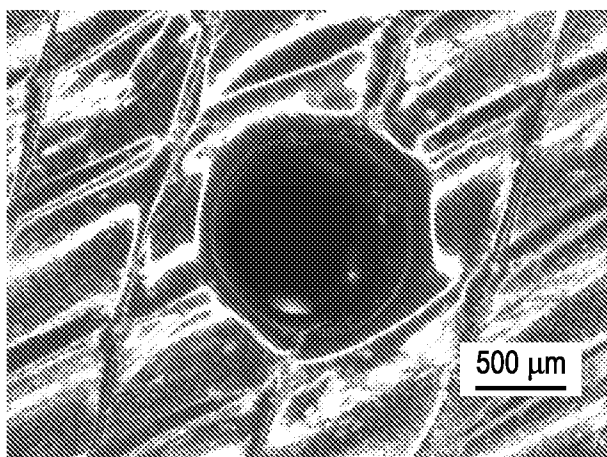


FIG. 4B

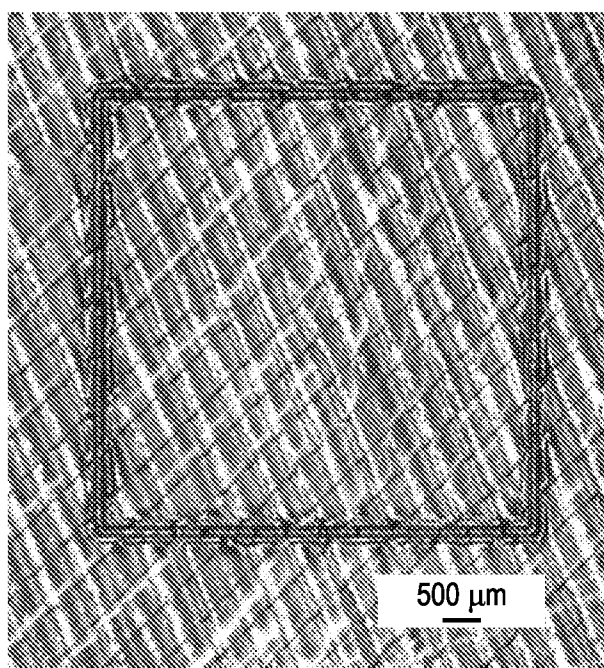
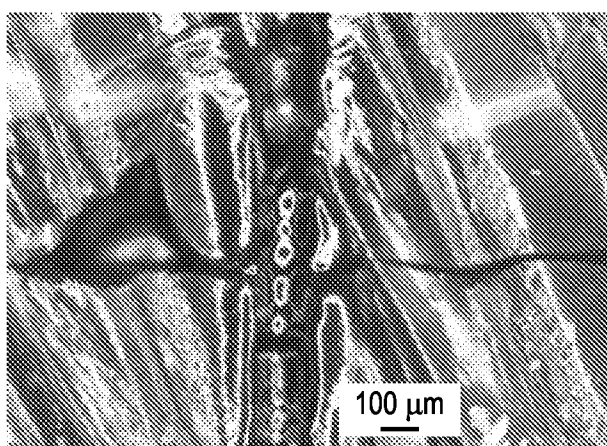


FIG. 4C



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FIG. 5A

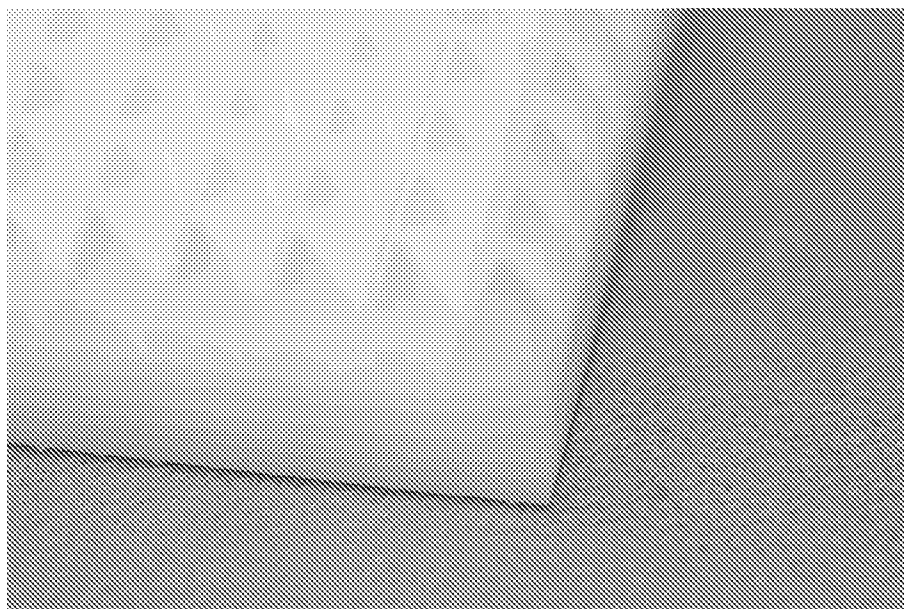
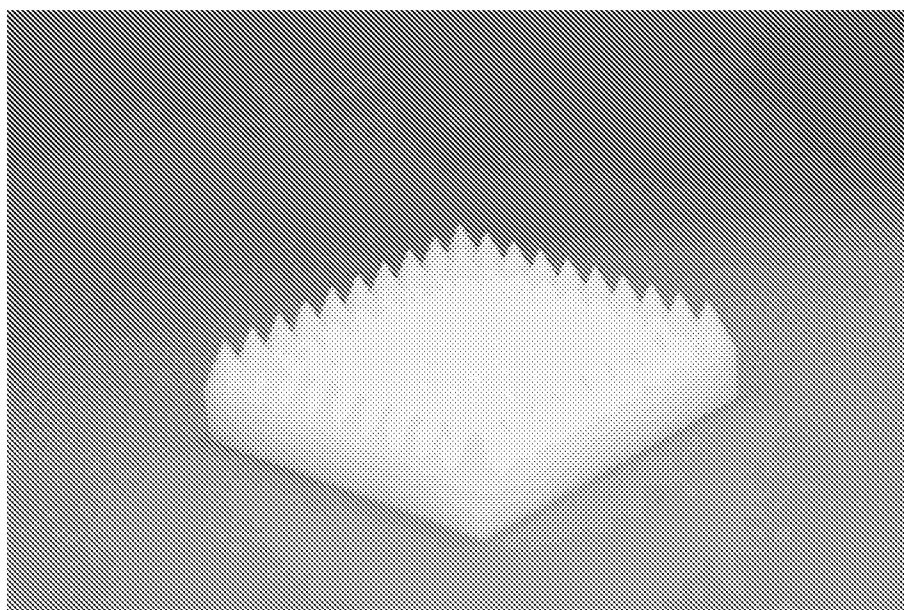
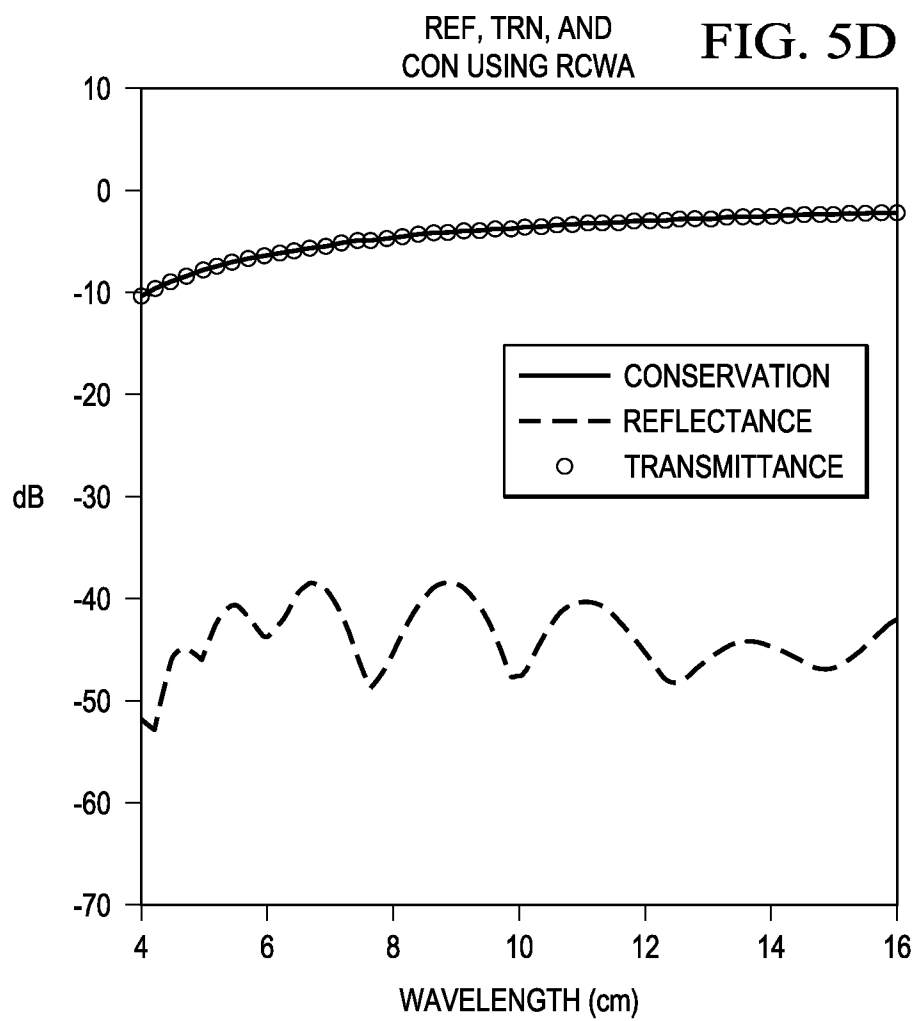
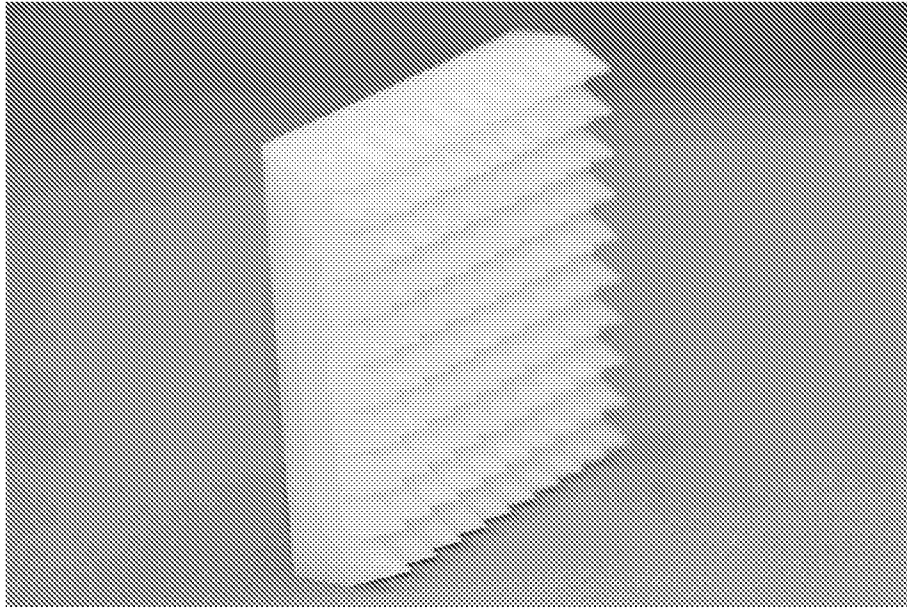


FIG. 5B



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FIG. 5C



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FIG. 6A

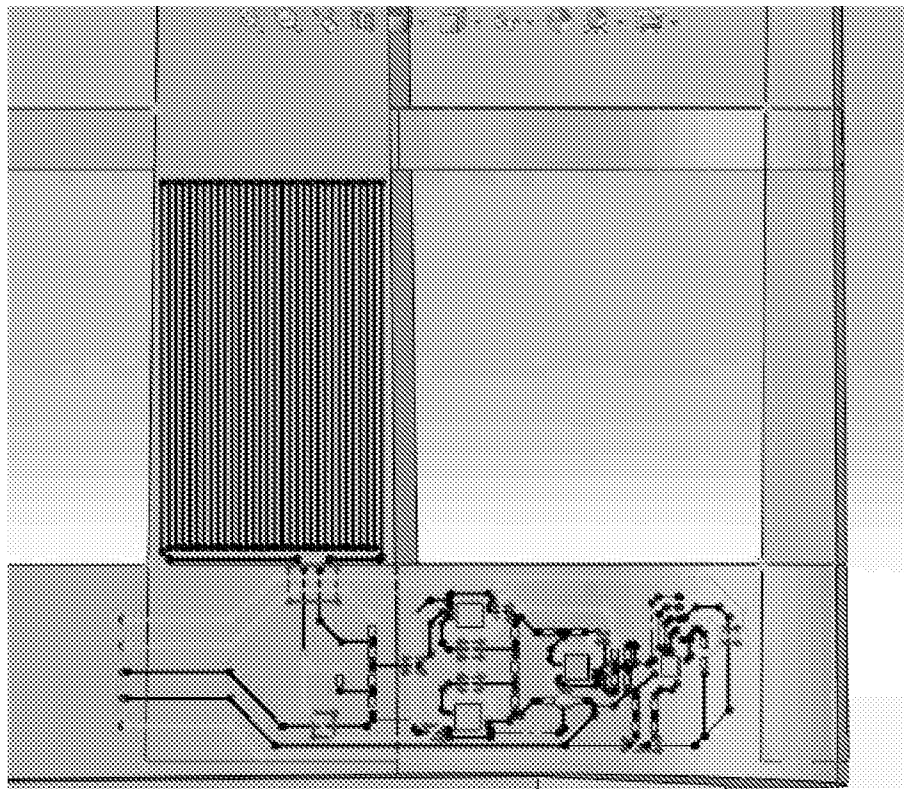
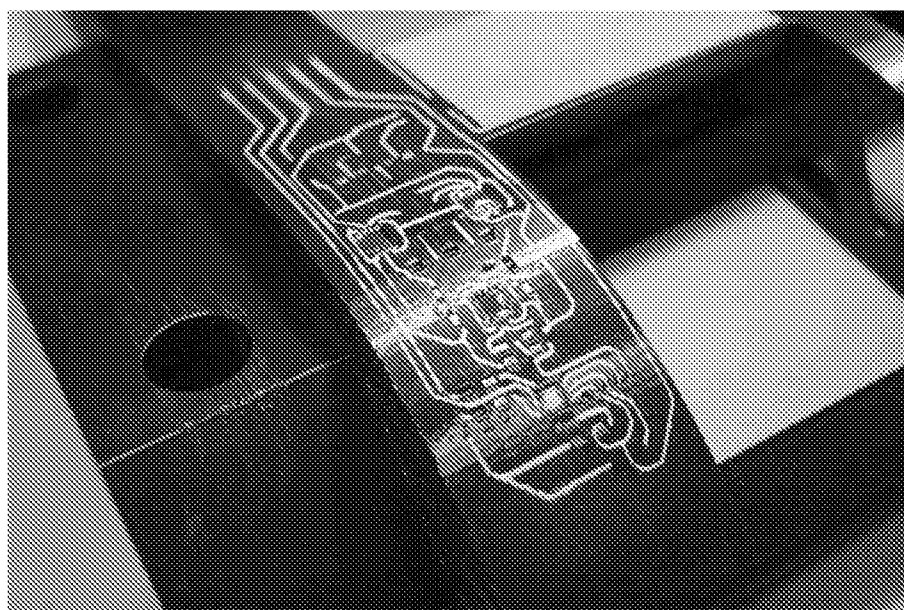


FIG. 6B



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FIG. 6C

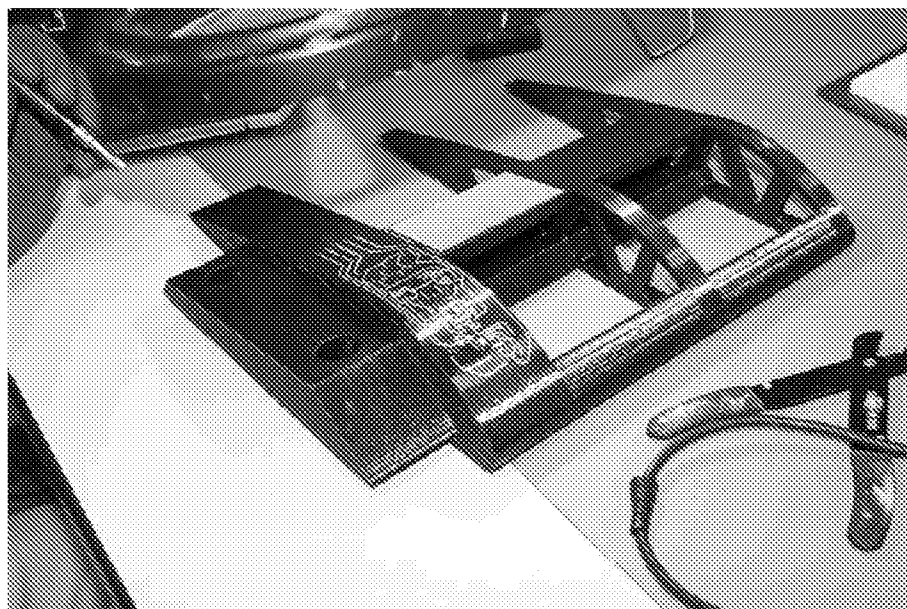
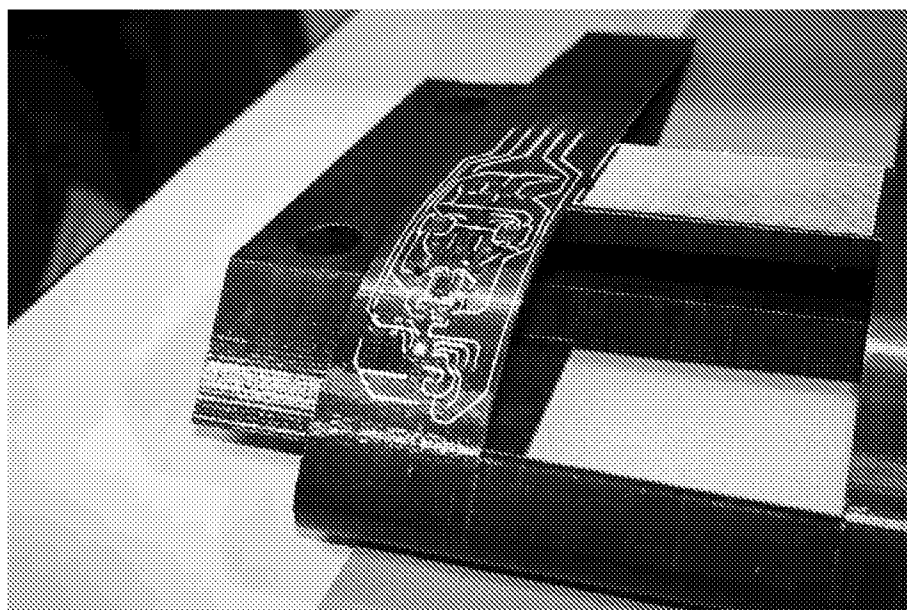
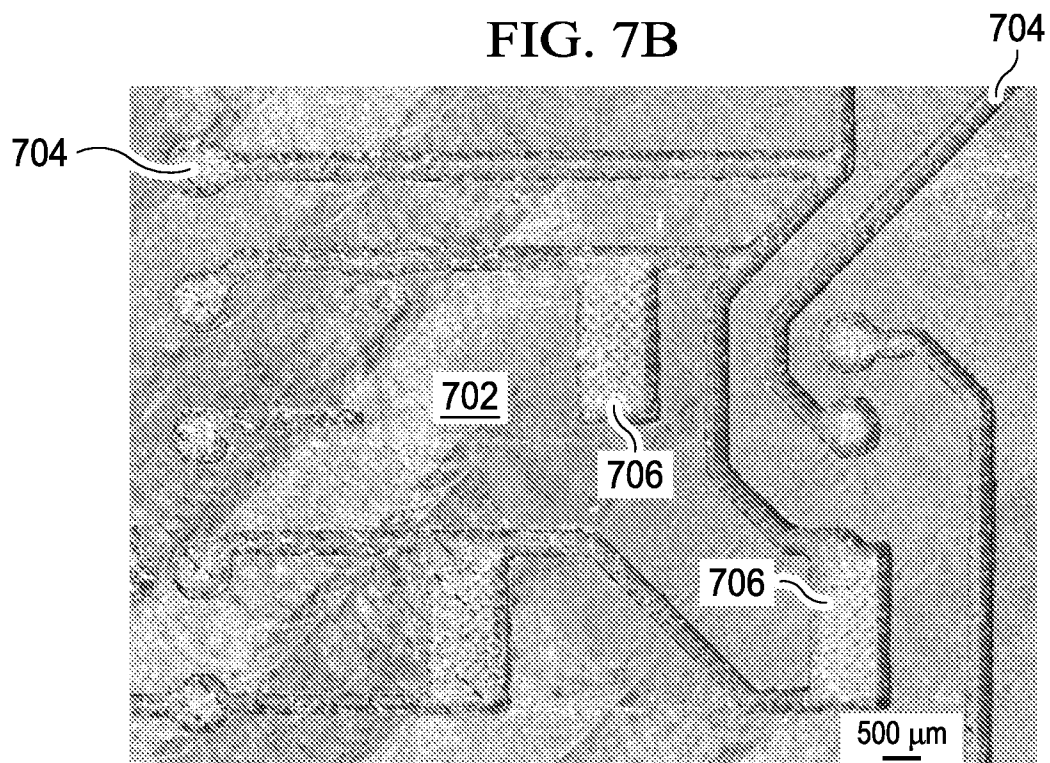
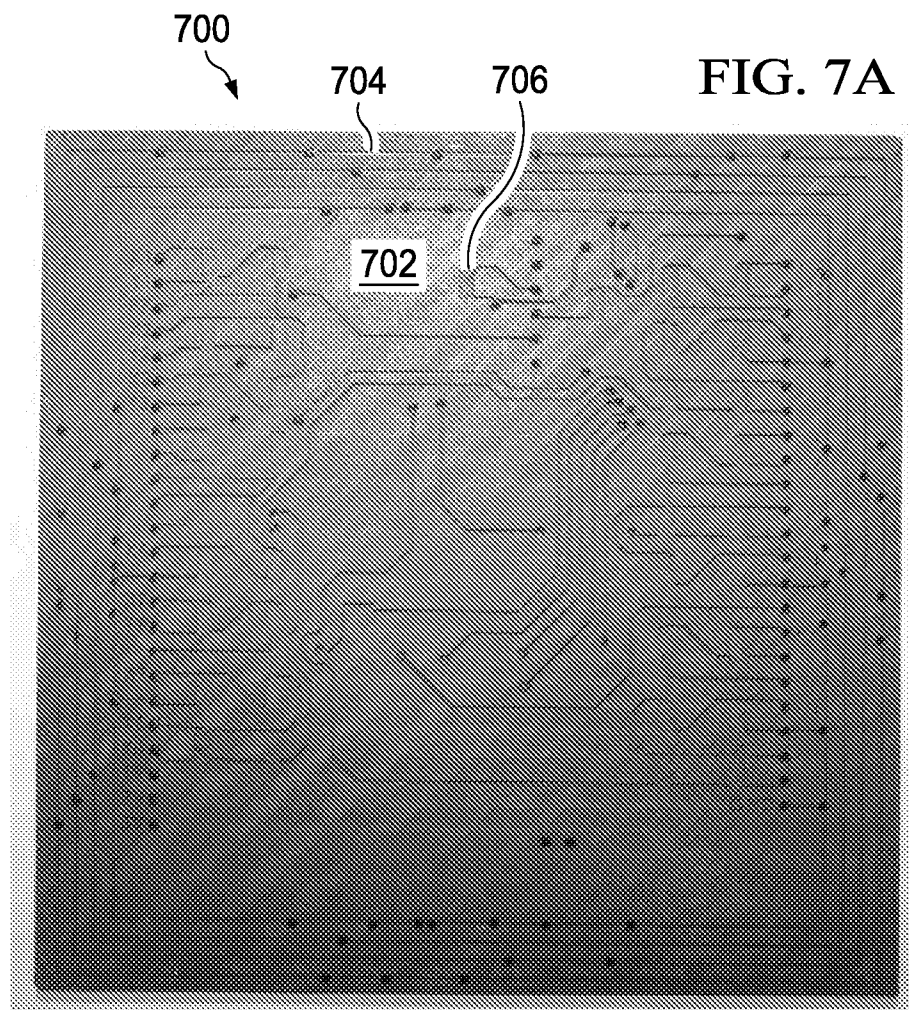


FIG. 6D

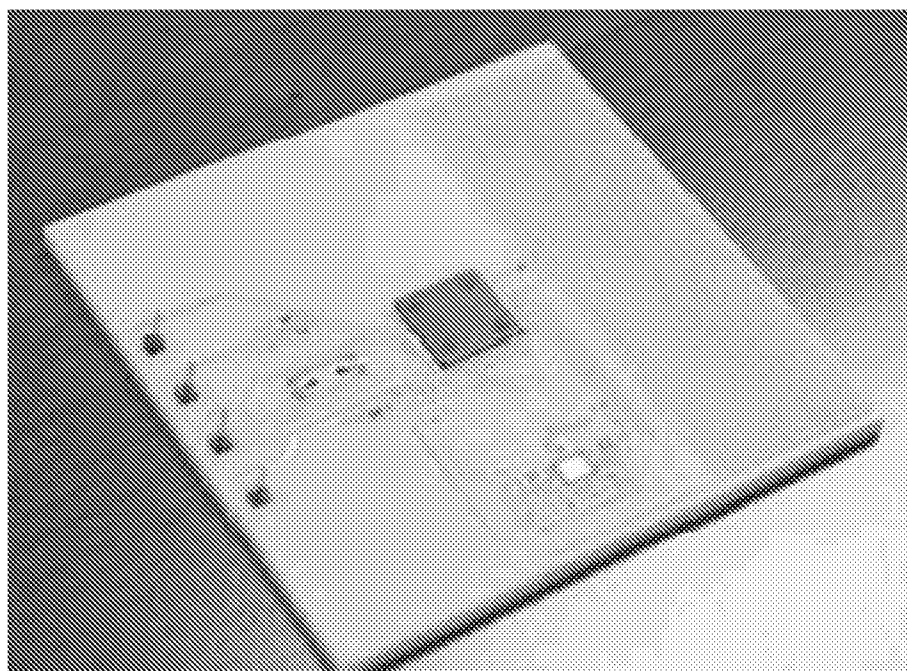


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FIG. 8



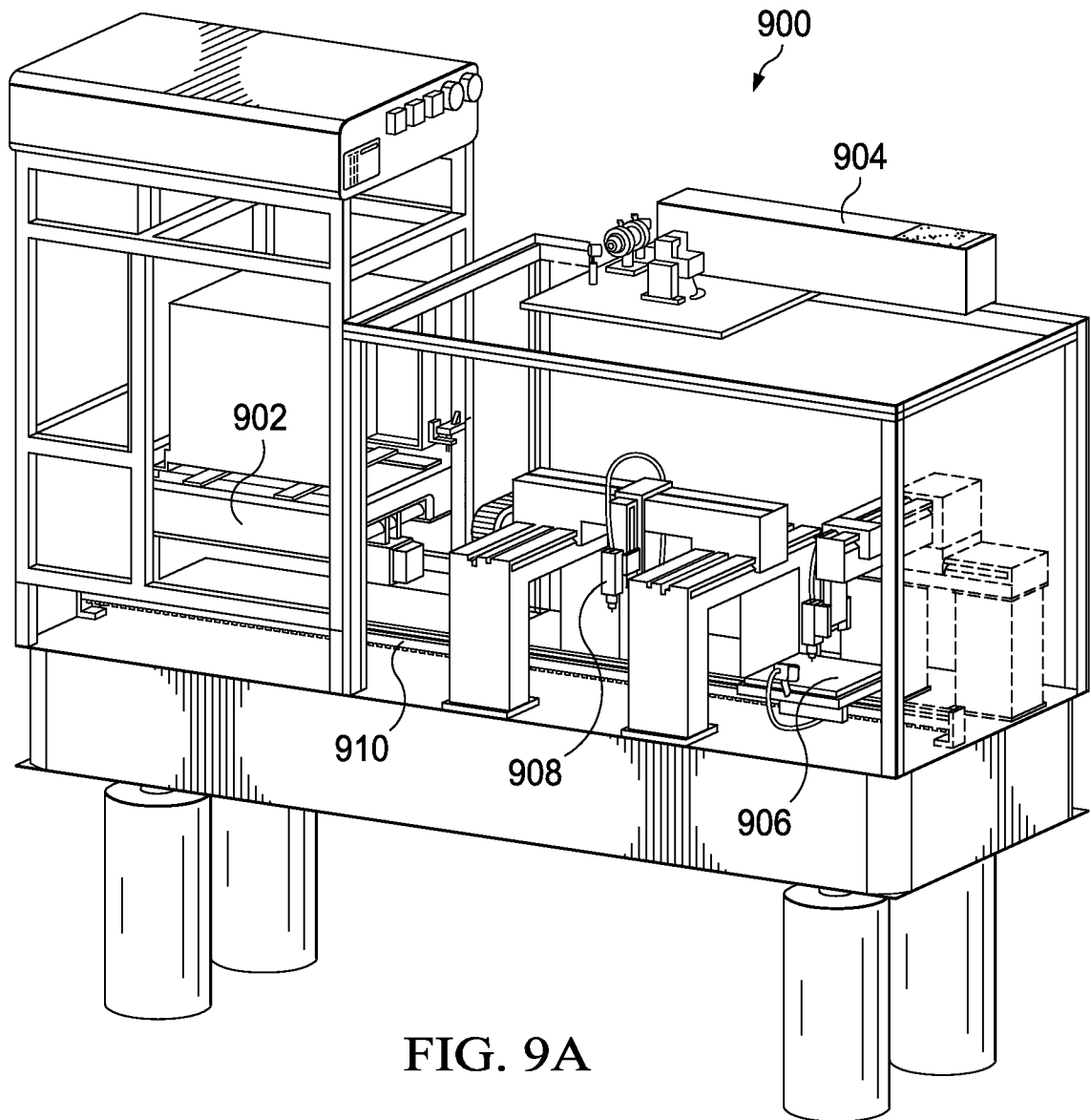


FIG. 9A

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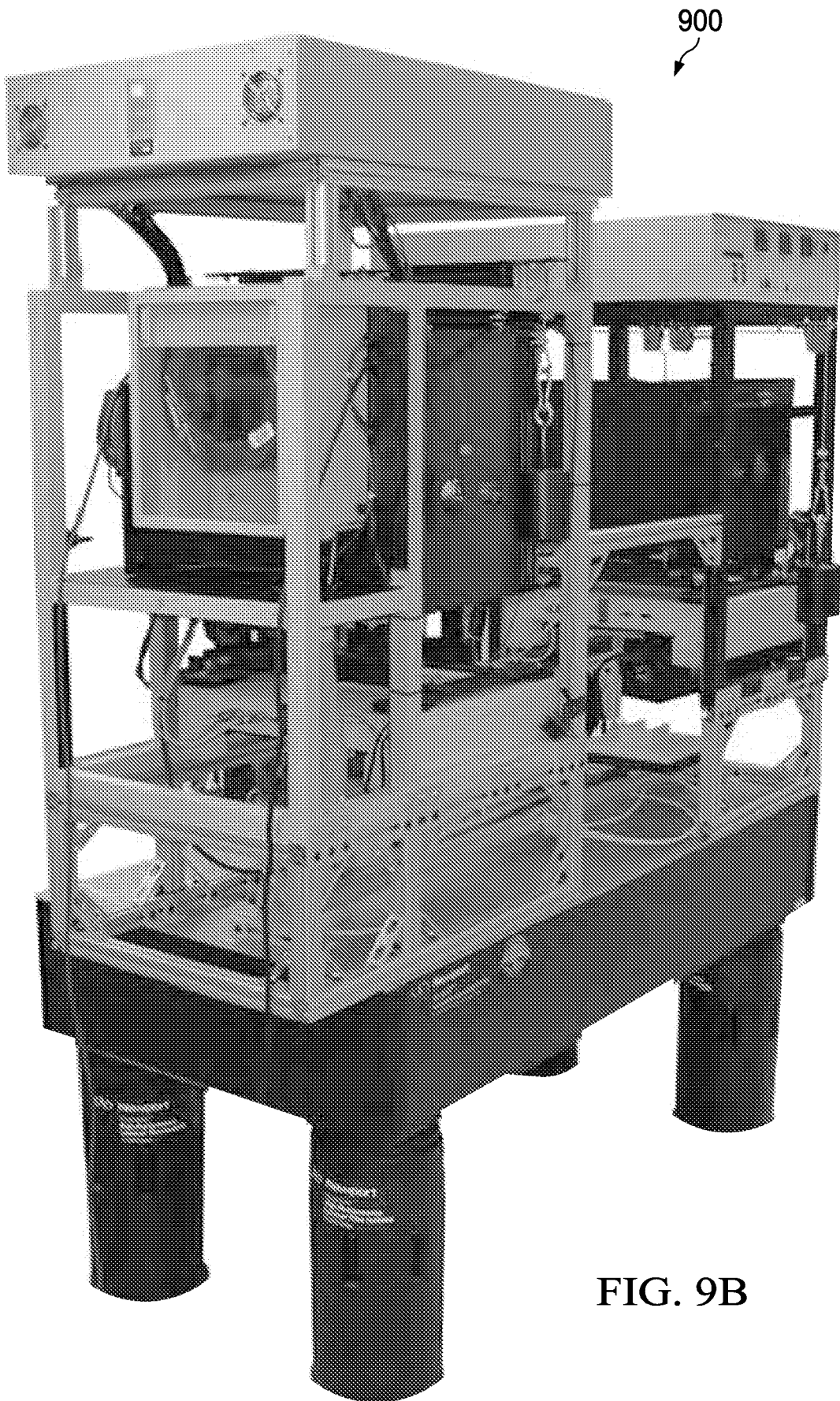


FIG. 9B

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FIG. 9C

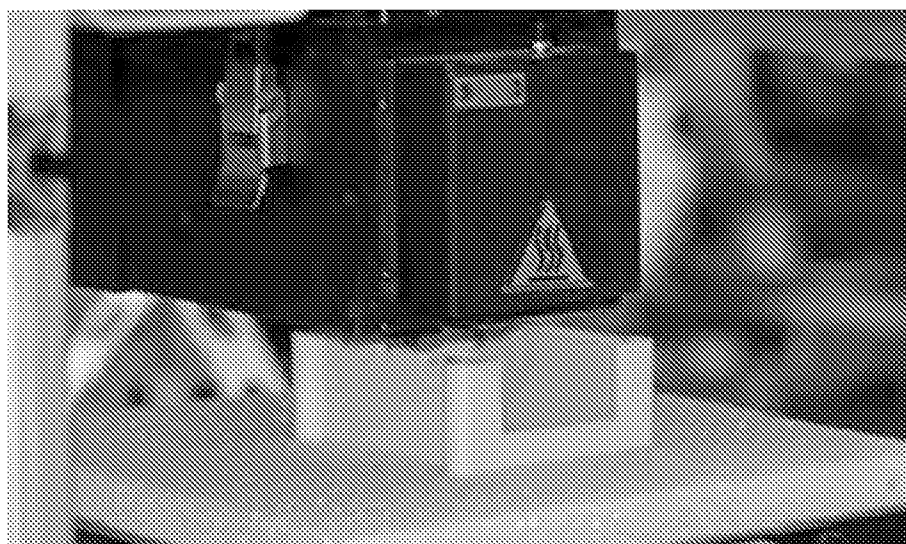
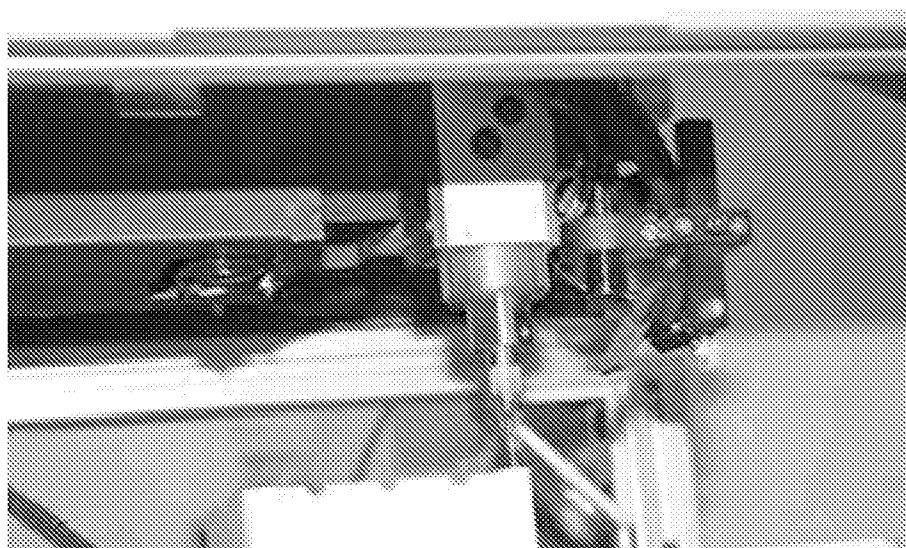


FIG. 9D



INTERNATIONAL SEARCH REPORT

International application No.
PCT/US2012/072100**A. CLASSIFICATION OF SUBJECT MATTER****HOIL 21/28(2006.01)i, HOIL 21/768(2006.01)1**

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

HOIL 21/28; HOIL 23/31; G06F 15/46; HOIL 21/208; HOIL 21/98; C08J 5/18; C08J 7/18; H05K 1/03; HOIL 21/44

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Korean utility models and applications for utility models

Japanese utility models and applications for utility models

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)

eKOMPASS(KIPO internal) & Keywords: layer-by-layer, interconnect, cavity and three-dimension

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	US 2010-0055895 A1 (ZAFIROPOULOS, ARTHUR W. et al.) 04 March 2010 See abstract ; paragraphs [0029] , [0039] -[0045] , [0059] and figures 1A-1H.	1-70
A	US 2008-0224293 A1 (HIN, KEONG BUN) 18 September 2008 See abstract ; paragraphs [0039] -[0045] , [0062] ; claim 1 and figures 4-5C , 17.	1-70
A	US 5121329 A (CRUMP, S. SCOTT) 09 June 1992 See abstract ; column 4, line 56 - column 9, line 26; claims 1-14 and figure 1.	1-70
A	KR 10-2011-0088644 A (KOOKMIN UNIVERSITY INDUSTRY ACADEMY COOPERATION FOUNDATION) 04 August 2011 See abstract ; paragraphs [0010] -[0035] ; claim 1 and figure 1.	1-70
A	KR 10-2011-0134701 A (EWAH UNIVERSITY-INDUSTRY COLLABORATION FOUNDATION) 15 December 2011 See abstract and paragraphs [0003] , [0009H0010] .	1-70
A	US 2007-0187137 A1 (ISEBO, KAZUHIRO) 16 August 2007 See abstract and claims 1, 5.	1-70

☐ Further documents are listed in the continuation of Box C.☒ See patent family annex.

* Special categories of cited documents:

"A" document defining the general state of the art which is not considered to be of particular relevance

"E" earlier application or patent but published on or after the international filing date

"L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of citation or other special reason (as specified)

"O" document referring to an oral disclosure, use, exhibition or other means

"P" document published prior to the international filing date but later than the priority date claimed

"T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention

"X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone

"Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art

"&" document member of the same patent family

Date of the actual completion of the international search

25 April 2013 (25.04.2013)

Date of mailing of the international search report

26 April 2013 (26.04.2013)

Name and mailing address of the ISA/KR

Korean Intellectual Property Office
189 Cheongsa-ro, Seo-gu, Daejeon Metropolitan
City, 302-70 1, Republic of Korea

Facsimile No. 82-42-472-7140

Authorized officer

CHOI, Sang Won

Telephone No. 82-42-481-8291



INTERNATIONAL SEARCH REPORT

Information on patent family members

International application No.

PCT/US2012/072100

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
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